

Customer No. 22,852
Attorney Docket No.: 04329.3161

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Kenji KAWANO et al.) Group Art Unit: Not Yet Assigned
Serial No.: Not Yet Assigned) Examiner: Not Yet Assigned
Filed: October 10, 2003)
For: METHOD OF PROCESSING A)
SUBSTRATE, HEATING APPARATUS, AND)
METHOD OF FORMING A PATTERN)

MAIL STOP PATENT APPLICATION
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)

Pursuant to 37 C.F.R. §§1.56 and 1.97(b), applicants bring to the Examiner's attention the documents listed on attached Form PTO-1449. With exception of the U.S. patents, copies of the listed documents are attached. Applicants respectfully request that the Examiner consider the documents listed on attached Form PTO-1449 and indicate that they were considered by making an appropriate notation on this form. This Information Disclosure Statement is being filed with the above-referenced application.

The following is a concise statement of relevance of the non-English language documents:

1. Japanese Patent Publication No. 2000-146444 - discloses an apparatus for heating a substrate with an inner plate having a large number of openings.

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2. Japanese Patent Publication No. 11-038644 - discloses a method to reduce the amount of evaporated acid by heating a substrate under high pressure in a heating chamber. The relevance of this document is also discussed at page 3 of the specification of the present application.

Also, an English-language abstract of each document is enclosed

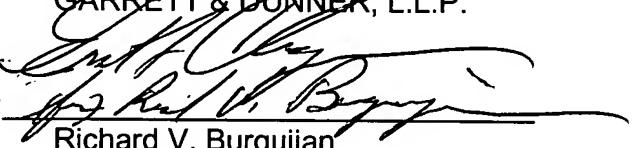
This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the listed documents are material or constitute "prior art." If the Examiner applies any of the documents as prior art against any claim in the application and applicants determine that the cited documents do not constitute "prior art" under United States law, applicants reserve the right to present to the office the relevant facts and law regarding the appropriate status of such documents. Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should one or more of the documents be applied against the claims of the present application.

If there is any fee due in connection with the filing of this Statement, please charge the fee to our Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

By:


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Dated: October 10, 2003

Enclosures
RVB/FPD/sci

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INFORMATION DISCLOSURE CITATION

Atty. Docket No.	04329.3161	Serial No.	Not Yet Assigned
Applicants	Kenji KAWANO et al.		
Filing Date	October 10, 2003	Group:	Not Yet Assigned

U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate
	6,265,696	07/24/01	SAKURAI et al.			
	6,301,435	10/09/01	ITO et al.			
	6,333,493	12/25/01	SAKURAI et al.			
	6,550,990	04/22/03	SAKURAI et al.			

FOREIGN PATENT DOCUMENTS

	Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
	11-038644	02/12/99	JAPAN			ABSTRACT
	2000-146444	05/26/00	JAPAN			ABSTRACT

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

KAWANO, K. et al., "Apparatus For Processing Substrate and Method of Processing The Same", U.S. Patent Application No. 10/026,419, filed December 26, 2001.
KIHARA, N. et al., "Effect of Acid Evaporation in Chemically Amplified Resists on Insoluble Layer Formation", Journal of Photopolymer Science and Technology, Vol. 8, No. 4, pp. 561-569, (1995).

Examiner	Date Considered
*Examiner:	Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.
Form PTO 1449	Patent and Trademark Office - U.S. Department of Commerce